

Formation of vacancy clusters during copper diffusion in semiinsulating GaAs

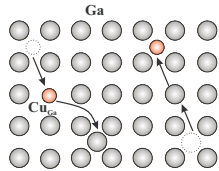
K. Petters*, J. Gebauer, H.S. Leipner, R. KrauseRehberg

Introduction

- Cu - most important impurity (contamination) in GaAs
- electrically active as acceptor $\text{Cu}_{\text{Ga}}^{2-}$

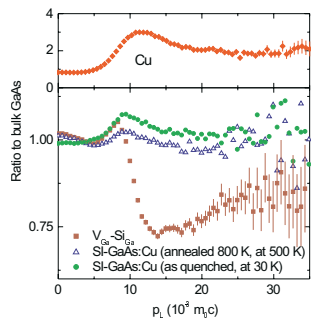
- max. solubility: $6 \times 10^{18} \text{ cm}^{-3}$ at 1100°C [1]

- fast diffusion [1] via kick-out mechanism [2]



- This work: understanding diffusion process and related defects (vacancies) in more detail

Doppler coincidence measurements



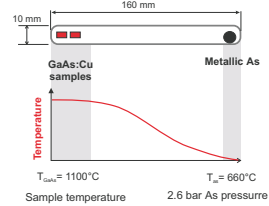
Normalized annihilation momentum distribution

Shapes of GaAs:Cu similar to Cu but different from that of $\text{V}_{\text{Ga}}\text{-Si}_{\text{Ga}}$, high positron lifetime in annealed material \rightarrow Cu neighbored to annihilation site

Annihilation next to Cu also in as-quenched material and lifetime $< \tau_{\text{bulk}}$ \rightarrow direct identification of Cu as shallow positron trap?

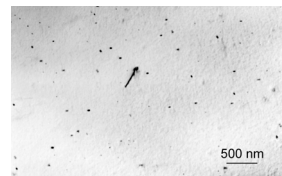
Experimental

- etching SI-GaAs with bromine-methanol and HCl
- covering by Cu with varying thickness (evaporation in UHV)

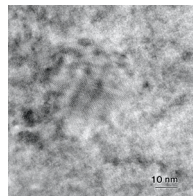


- annealing in two zone furnace
- quenching into water to room temperature (60 K/s)
- Hall and thermoprobe measurements
- PAS: Lifetime spectroscopy (FWHM = 240 ps)
- Doppler coincidence spectroscopy (Ge-Ge, 1.03 keV)
- Transmission electron microscopy (TEM)

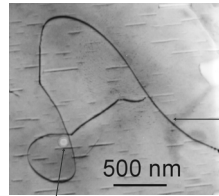
TEM investigations of structural defects



Bright-field image with small dislocation loops of interstitial type



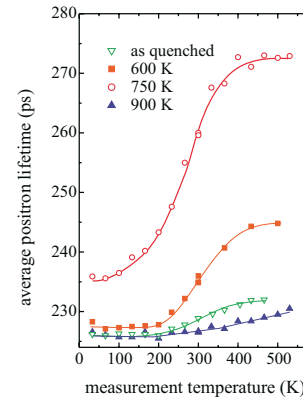
High resolution image: Cu_{Ga} , [3] or Cu_{As} , [4]



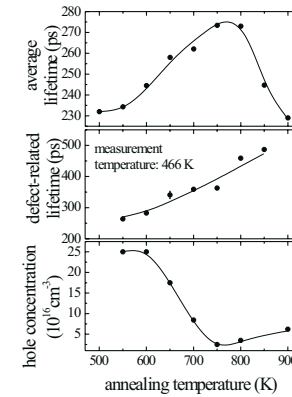
perfect dislocation loop

- All images: $[\text{Cu}] = 6 \times 10^{18} \text{ cm}^{-3}$, as quenched
- no further change during annealing
- \rightarrow no direct influence of extended defects on positron trapping

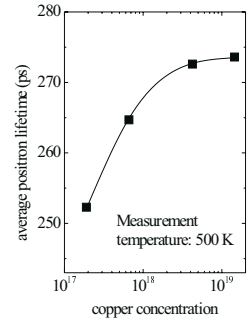
Positron lifetime measurements



Temperature-dependent measurement after annealing



Behavior at high temperature (no influence from shallow traps)



Dependence on Cu concentration

Conclusions

- after Cu-indiffusion and quenching no vacancy-type defects are registered
- shallow traps are found which are directly related to Cu
- during annealing vacancy clusters grow and dissolve above 850 K
- vacancies and clusters are decorated with Cu
- Distance between possible annihilation centres seen in TEM is much longer than mean positron diffusion length so they have no influence on positron trapping

References

- [1] R.N. Hall, J.H. Racette, J. Appl. Phys. 35 (1964) 379.
- [2] F.C. Frank, D. Turnbull, Phys. Rev. 104 (1956) 617.
- [3] R. Leon, P. Werner, K.M. Yu, M. Kaminska, E.R. Weber, Appl. Phys. A 61 (1995) 7.
- [4] H. S. Leipner, R. F. Scholz, F. Syrowatka, J. Schreiber, P. Werner, Phil. Mag. A (1999).